

MICRO-503

MEMS practicals II

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Cursus	Sem.	Type
Microtechnics	MA2, MA4	Opt.

Language of teaching	English
Credits	2
Withdrawal Session	Unauthorized Summer
Semester	Spring
Exam	During the semester

Workload 60h

Weeks 14

Hours 2 weekly

Practical work 2 weekly

Number of positions

Il n'est pas autorisé de se retirer de cette matière après le délai d'inscription.

Summary

Objective of this practical is to apply in specific experimental settings the knowledge acquired in various MEMS related class

Content

The practical is organized in several lab experiments.

The part I (winter semester) is dedicated to MEMS technology and MEMS simulation:

- Finite element simulation of MEMS
- Design of MEMS actuators
- Fabrication of MEMS actuators
- Characterization of MEMS actuators
- Noise in sensors

The part 2 (spring semester) is dedicated to sensors:

- capacitive accelerometer
- ISFET
- Glucose sensor
- piezoresistive pressure sensor • Electrokinetic chip

Learning Outcomes

By the end of the course, the student must be able to:

- Conduct an experiment
- Report on experiments

Transversal skills

- Demonstrate the capacity for critical thinking

Teaching methods

Practicals supervised by assistants

Assessment methods

Based on work in the lab, answer to questions during experimental sessions and quality of the report

Supervision

Office hours	Yes
Assistants	Yes

Resources

Moodle Link

- <https://go.epfl.ch/MICRO-503>